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Supporting Information

3 **Activating the S surfaces via Reversing the electron supply**
4 **direction for fast Hydrogen Sensing**

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12

13 **1.Experiment detail**

14 **1.1 XAFS Measurements:**

15 The X-ray absorption fine structure data were collected at 1W1B station in Beijing
16 Synchrotron Radiation Facility (BSRF). The storage rings of BSRF was operated at 2.5
17 GeV with a maximum current of 250 mA. The X-ray absorption near edge structure
18 (XANES) data were recorded in fluorescence mode. All samples were pelletized as
19 disks of 13 mm diameter using poly(1,1-difluoroethylene) powder as a binder. The
20 acquired extended X-ray absorption fine structure (EXAFS) data were processed
21 according to the standard procedures using the ATHENA module implemented in the
22 IFEFFIT software packages. ¹The EXAFS spectra were obtained by subtracting the
23 post-edge background from the overall absorption and then normalizing with respect to
24 the edge-jump step. Subsequently, $\chi(k)$ data in the k-space were Fourier transformed to
25 real (R) space using a Hanning window ($dk = 1.0 \text{ \AA}^{-1}$) to separate the EXAFS
26 contributions from different coordination shells.

27 **1.2 Ex situ XPS experiments:**

28 *Ex situ* XPS measurements were carried out on X-ray photoelectron spectroscopy (XPS,
29 ESCALAB 250Xi, Thermofisher Scientific) and binding energies were calibrated the
30 of the elements by C 1s (284.6 eV). During the test, the sample was first mounted on a
31 transfer bar and then transferred to the reaction chamber. Next, a gold-plated copper
32 seal was installed to seal the reaction chamber. Then, the target temperature (170°C) is
33 set and the corresponding air is injected for pretreatment for 5 minutes. Finally, the
34 reaction chamber is evacuated, and then transferred directly to the analysis chamber for

35 testing and analysis. The data obtained is the XPS spectra in air. The reaction chamber
36 was transferred out of the analysis chamber. The corresponding mixture of H₂ gas and
37 air is injected for pretreatment for 5 minutes (H₂ in the gas mixture at a concentration
38 of 2%). Then, the reaction chamber was vacuumed, and then directly transferred to the
39 reaction chamber for testing and analysis. The obtained data is XPS spectra in H₂.

40 **1.3 *In situ Raman experiments:***

41 The Raman spectra were obtained on a Renishaw spectrometer (Raman, INVIA). The
42 sample was first placed on a silicon wafer in the in-situ reactor. Then a mixture of H₂
43 gas and air was injected and the Raman spectrum is collected (2% of H₂ in the gas
44 mixture). Finally, data is collected every 30 s and the last data is collected at 150 s to
45 end the test.

46 **1.4 *Gas-sensing measurement:***

47 The gas-sensitive material was coated on the interdigital electrode of Micro Electro
48 Mechanical System (MEMS) chip. Assembled MEMS sensors were placed onto the
49 bottom of the chamber of LP-002A gas sensing system (Lingpan Electronics
50 Technology Co. Ltd., China). The gas sensing system were shown in Figure S14-S15.

51 The operating voltage of the test circuit is 10 V. The resistance of sensors was obtained
52 by detecting the voltage of the loading resistor in series. The resistance (R) of sensor
53 were calculated by the Eq. (1):

$$54 \quad R = \left(\frac{10 - V_{out}}{V_{out}} \right) \cdot R_L \quad (1)$$

55 Where 10 is the circuit voltage, V_{out} is the output voltage of the load resistance (R_L)
56 detected. The operating temperature of sensors was achieved by adjusting the heater

57 voltage. When the resistances kept stable, the test gas was injected into the 200 mL
58 chamber. The amount of injected gas can be obtained through the Eq. (2):

$$59 \quad C_x = \frac{V_x}{200} \cdot C \quad (2)$$

60

61 Where V_x (mL) is the gas volume extracted from the gas sampling bags by the micro
62 syringe, 200 is the volume of the test chamber, C is the standard concentration of gas
63 in gas sampling bags and the C_x is the different gas concentration in the test chamber.

64 The response value of sensors in a reducing atmosphere is defined as $\text{response} = R_a/R_g$.

65 The resistance of the sensor in the air is recorded as R_a and that in the test gas is R_g .

66 The selectivity coefficient (K) can be used to quantitatively assess the selectivity of the
67 sensor. The K value can be calculated by the Eq. (3):

$$68 \quad K = \frac{\text{response}_{SO_2}}{\text{response}_x} \quad (3)$$

69 where the response SO_2 is the response of the sensor in 5 ppm SO_2 and the response x
70 is the response of the sensor in 5 ppm other gases.

71 **1.5 Gas (H_2) Adsorption and Desorption Tests:**

72 The Quartz crystal microbalance (QCM) resonators were purchased from Chengdu

73 West Sensor Technology Co., Ltd. QCM measurement is composed of a thin slice of

74 quartz crystal with double-faced deposited silver electrodes. The mechanism of QCM

75 is based on the piezoelectric effect of quartz crystal oscillator, where there is a
76 quantitative relationship between the increasing mass change (Δm) and decreasing
77 frequency change (Δf). The quantitative relationship is in accordance with the
78 Sauerbrey equation: $\Delta f = -2.3 \times 10^{-6} \times f_0^2 \Delta m / A$. Where f_0 is the inherent oscillation
79 frequency of the chip (10^7 , Hz), A is the effective working area of the electrodes ($d=3$
80 mm).

81 **1.6 Methodology and calculation model:**

82 All DFT computations were performed in the Vienna ab initio simulation package
83 (VASP) ² under projector augmented wave (PAW) potentials to describe the
84 interactions. The generalized gradient approximation (GGA) ³ in the Perdew–Burke–
85 Ernzerhof (PBE) functional was used to treat the exchange-correlation between
86 electrons. The way of DFT-D3 ⁴ was adopted to correct van der Waals force. A cut-off
87 energy of 500 eV for plane wave expansions was used and all geometric structures were
88 set a 10 Å vacuum layer in the z-direction. The 10^{-5} eV for conventional energy and
89 0.02 eV \AA^{-1} for force under a $2 \times 2 \times 1$ sheet k-point mesh were taken as the convergence
90 criteria to optimize the structures. The electronic structures of the density of state (DOS)
91 were calculated with $3 \times 3 \times 1$ k-points. In all of the structure optimization, the bottom
92 half of the slab in the vertical z-direction was constrained, while the top half of the slab
93 and the adsorbates were fully relaxed. In this calculation, the ZnS (0 0 2) was modeled
94 by a 2×2 supercell. The adsorption energy (ΔE) of H_2 on the substrates can be given by
95 Eq. (4):

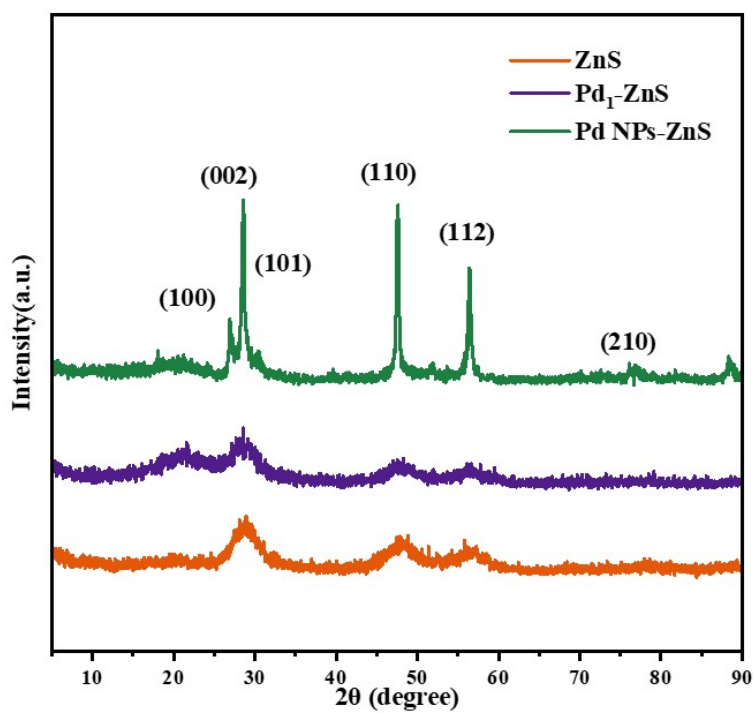
$$96 \Delta E = E_{\text{total}} - E_{H_2} - E_{\text{substrate}} \quad (4)$$

97 Where E_{total} , E_{H_2} , and $E_{\text{substrate}}$ are the energy of H_2 adsorption on the substrate, energy

98 of H_2 , and energy of substrate, respectively.

99 2. Supporting Figures and Tables

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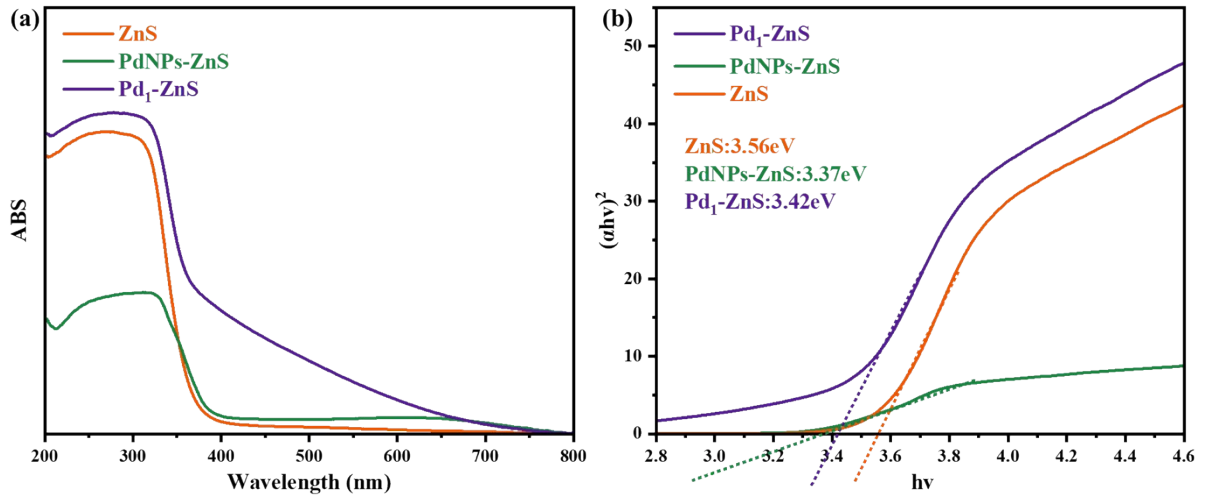


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Fig. S1. XRD pattern of the ZnS, Pd₁-ZnS and Pd NPs-ZnS.

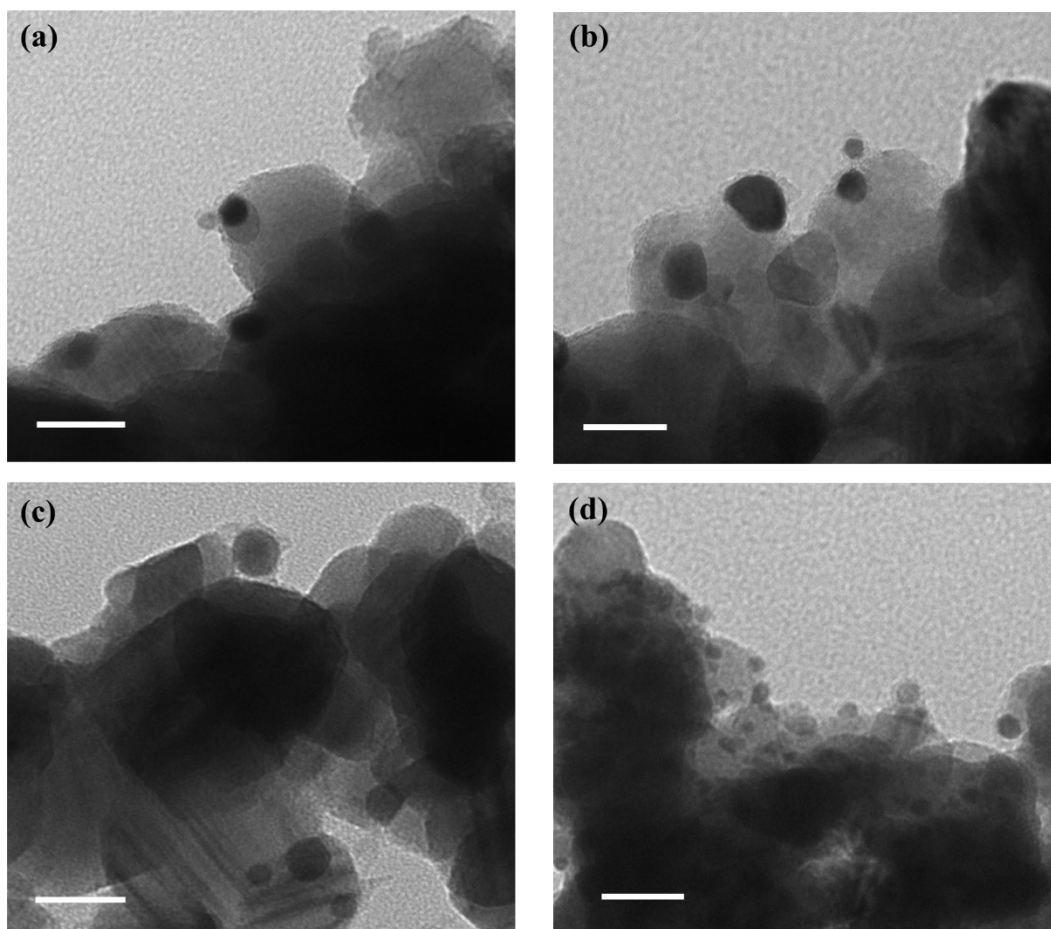
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105 **Fig. S2.** (a) UV-vis diffuse reflectance spectrum and (b) Kubelka-Munk function
 106 curve plotted against photon versus the energy of absorbed light of ZnS, Pd₁-ZnS and
 107 Pd NPs-ZnS.

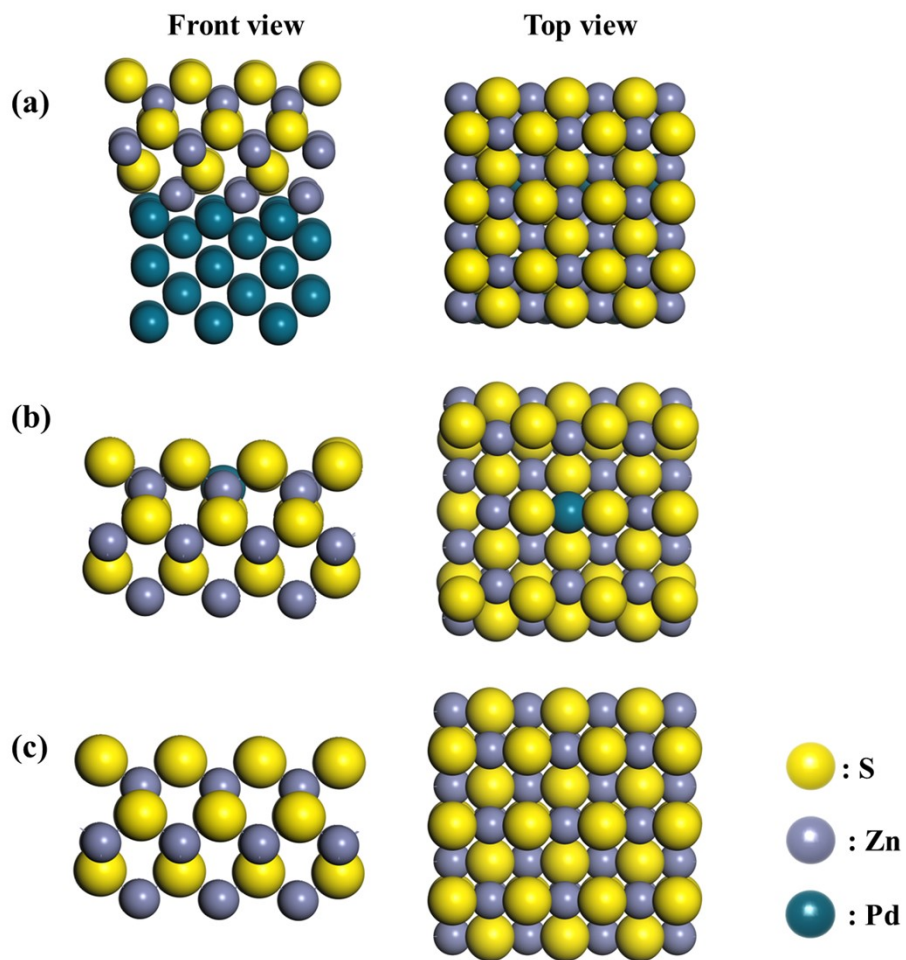
108 The relationship between $(\alpha hv)^2$ and photon energy $h\nu$ is obtained according to the
 109 formula $(\alpha hv)^2 = A (h\nu - E_g)$, where α , A, h and ν are the absorption coefficient,
 110 absorption constant, Plank constant and light frequency, respectively. Extrapolate the
 111 part of the spectra near the absorption edge, the intersection with the abscissas is
 112 obtained.



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115 **Fig. S3.** TEM images of Pd NPs-ZnS, scale bar is 25 nm.

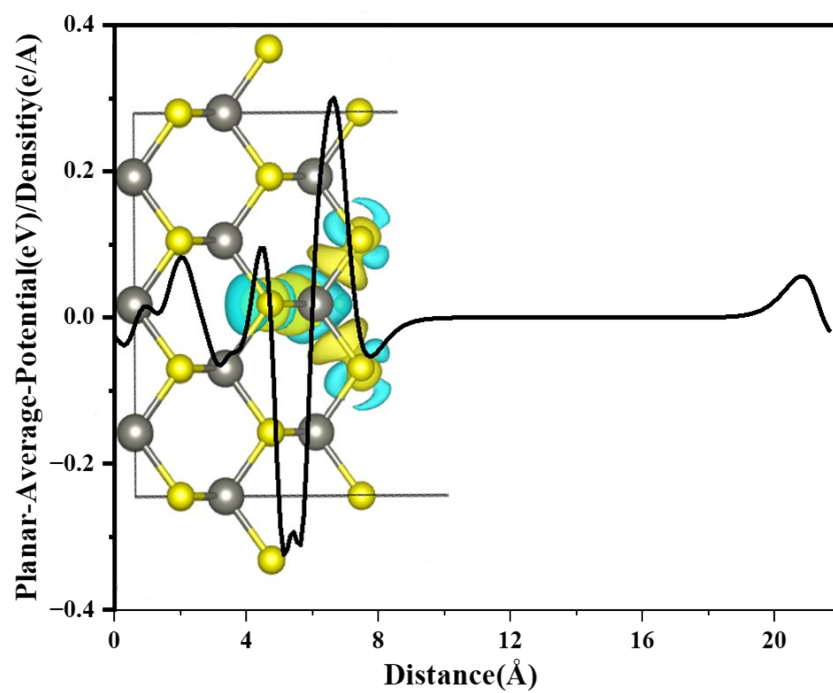
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118 **Fig. S4.** Structure models for (a) Pd NPs-ZnS (b) Pd₁-ZnS (c) ZnS.

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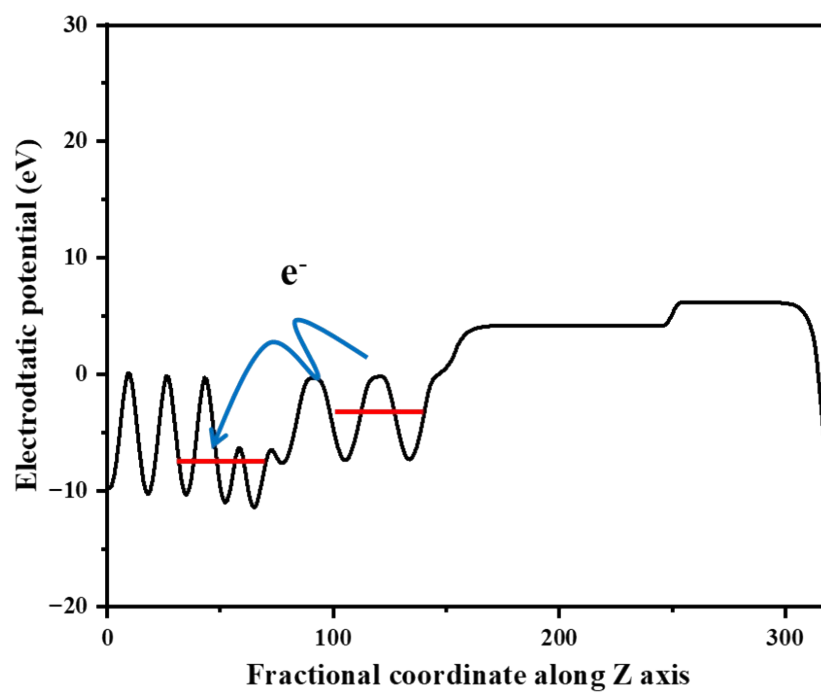


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121 **Fig. S5.** The planar-averaged electron density difference $\Delta\rho(z)$ of Pd₁-ZnS.

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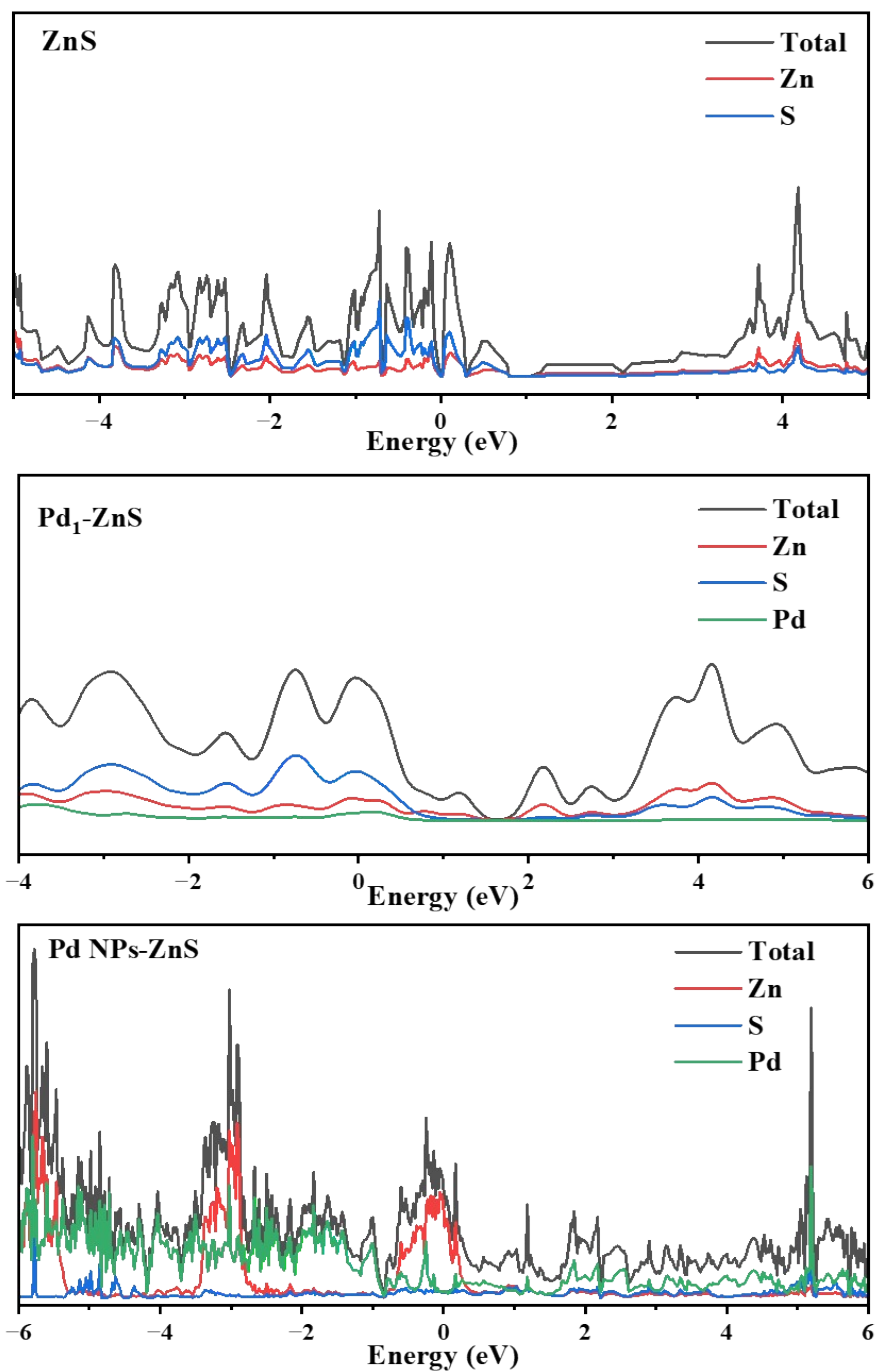
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124

125 **Fig. S6.** Work functions of Pd NPs-ZnS.

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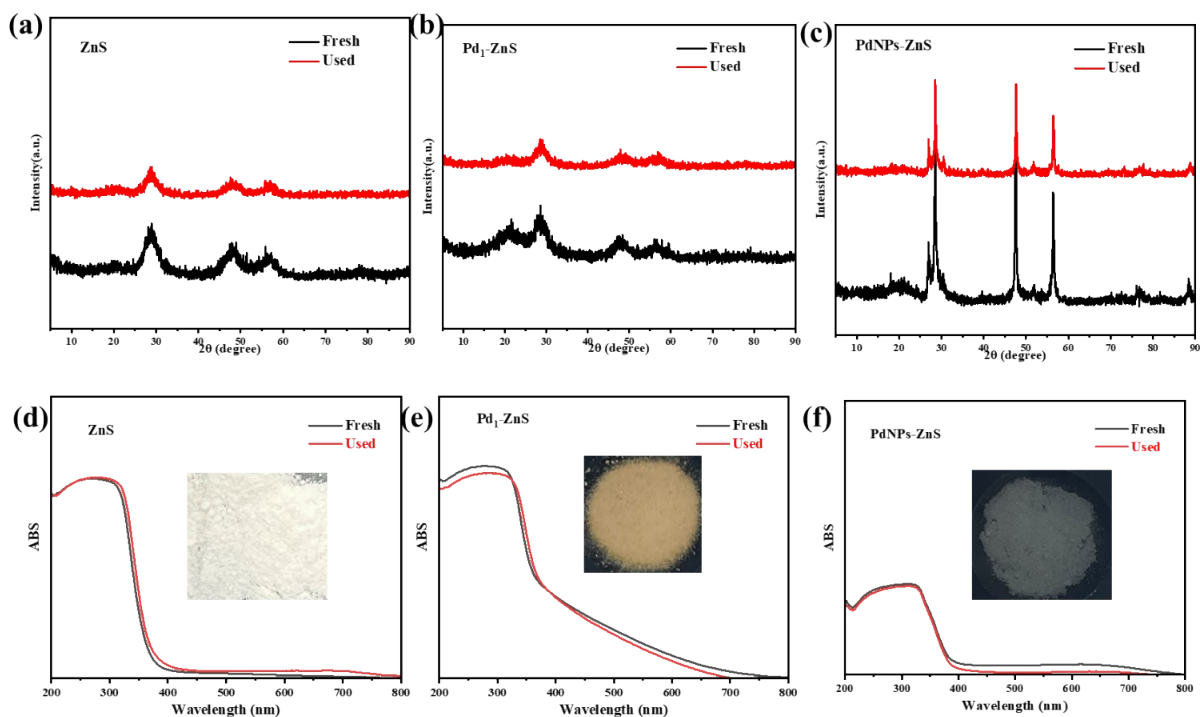


127

128 **Fig. S7.** The total density of states (TDOS) and projected density of state (PDOS) of
 129 ZnS, Pd₁-ZnS and Pd NPs-ZnS.

130 When electrons flow into a material, the Fermi-level of the material will increase, and
 131 when electrons flow out, the Fermi-level of the material will decrease.

132

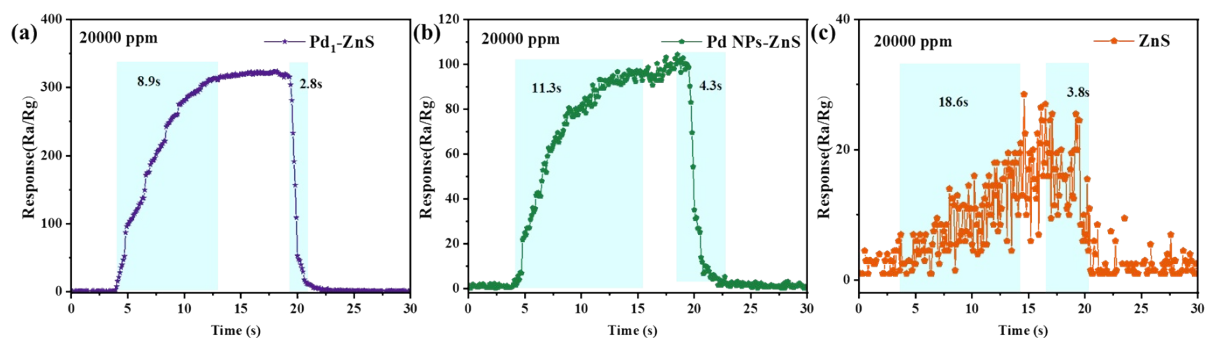


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134 **Fig. S8.** (a-c) XRD pattern of the ZnS and ZnS after 200°C for 2h, Pd₁-ZnS and Pd₁-
 135 ZnS after 170°C for 2h, Pd NPs-ZnS and Pd NPs-ZnS after 200°C for 2h. (d-f) UV-vis
 136 diffuse reflectance spectra of the ZnS and ZnS after 200°C for 2h, Pd₁-ZnS and Pd₁-
 137 ZnS after 170°C for 2h, Pd NPs-ZnS and Pd NPs-ZnS after 200°C for 2h.

138 XRD and UV-vis spectra show that the three materials can maintain the corresponding
 139 crystal structure at the corresponding optimum operating temperature.

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141

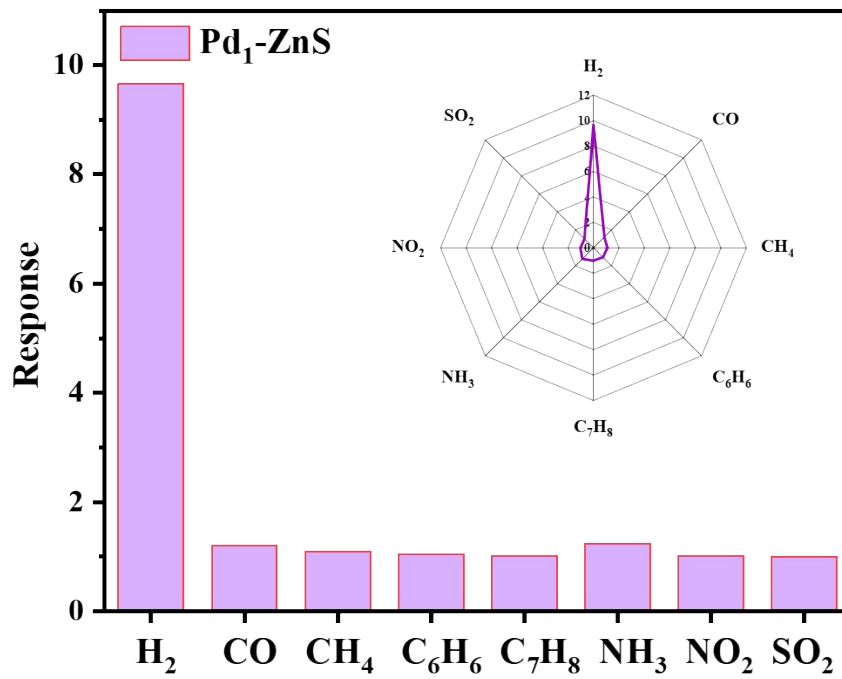
142 **Fig. S9.** Response transient of the Pd₁-ZnS, Pd NPs-ZnS and ZnS sensors to 20000

143 ppm H₂.

144 The response and recovery times of the Pd NPs-ZnS (11.3 s/4.3 s for 20000 ppm) and

145 ZnS (18.6s/3.8s for 20000 ppm) sensors are all longer than the response and recovery

146 times of Pd₁-ZnS sensors (8.9s/2.9s for 20000 ppm).



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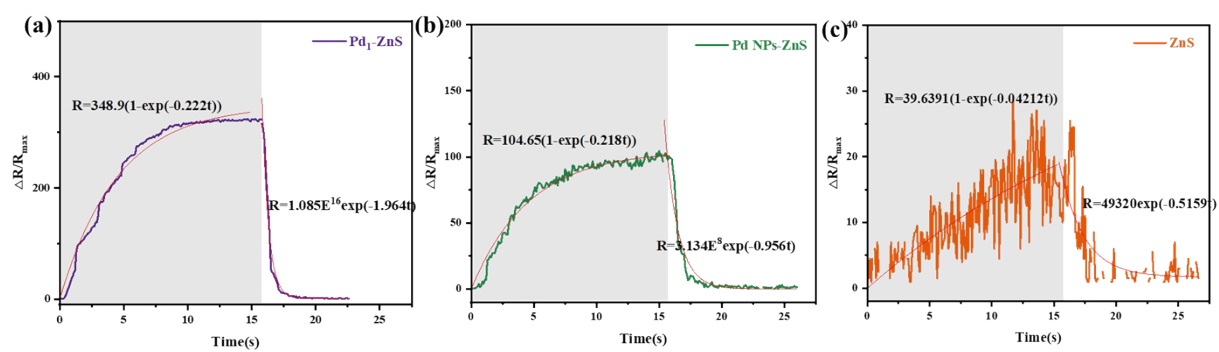
149 **Fig. S10.** Selectivity of Pd₁-ZnS sensors towards 20 ppm various gas species.

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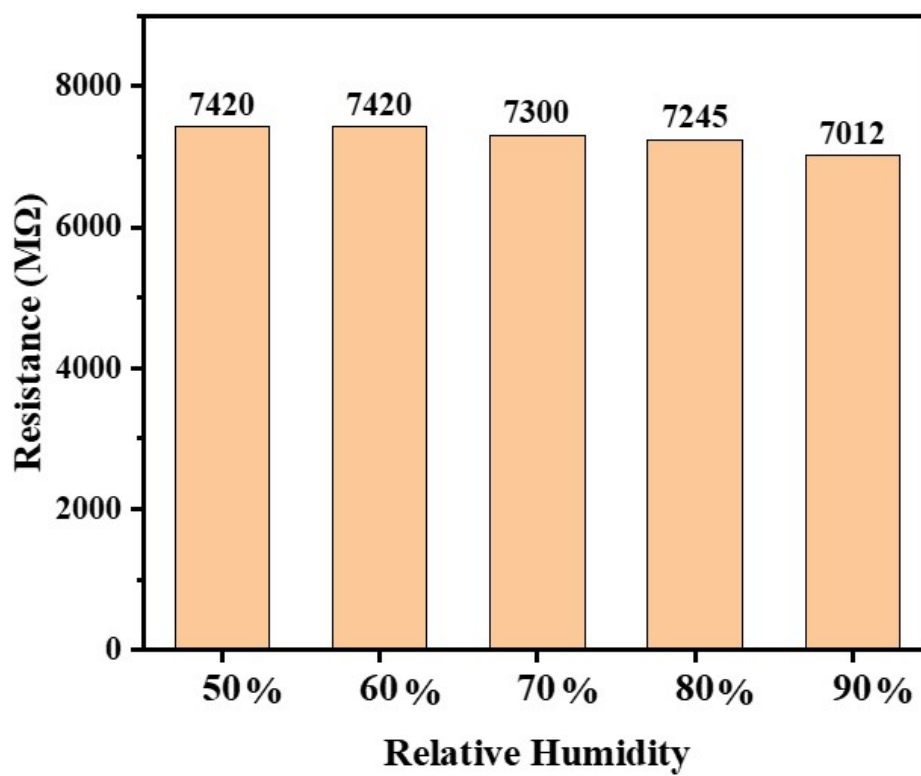


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155 **Fig. S11.** Dynamic response transitions and the corresponding response/recovery
156 fitting curves of the sensors for 20000 ppm of H₂ sensing.

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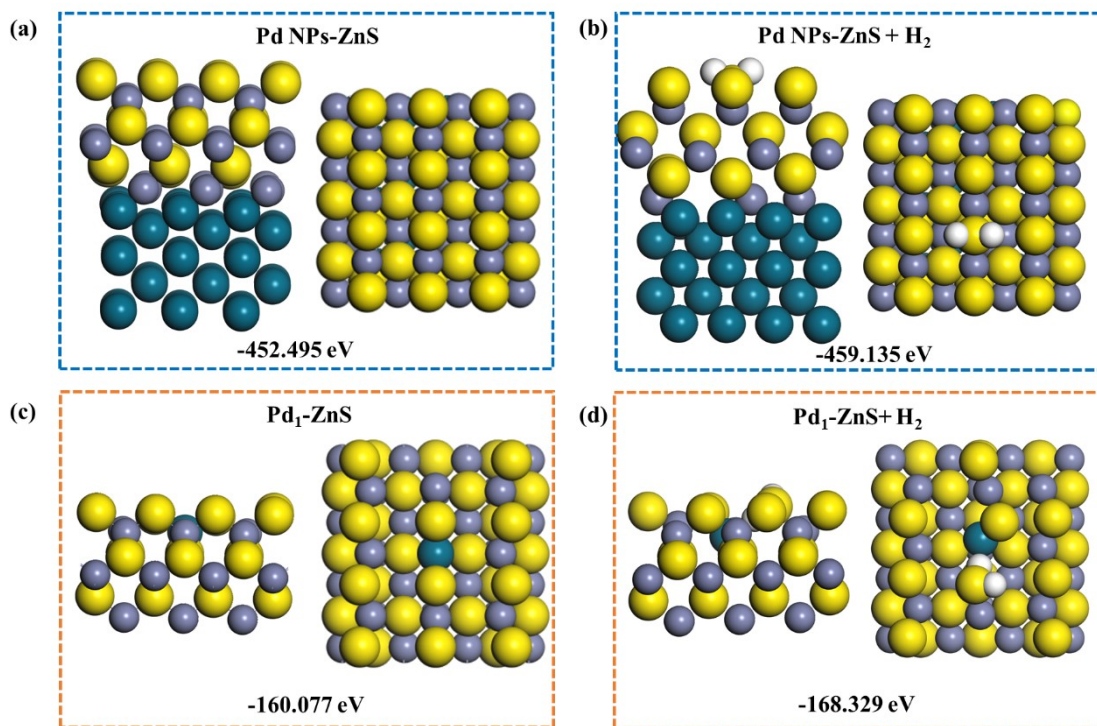


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160 **Fig. S12.** Baseline resistance at different relative humidity of Pd1-ZnS in air.

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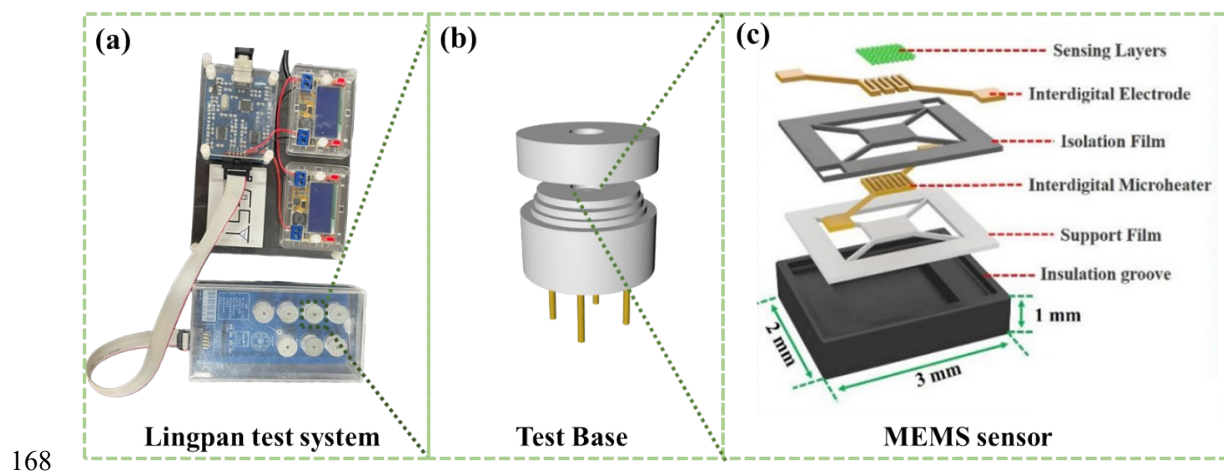
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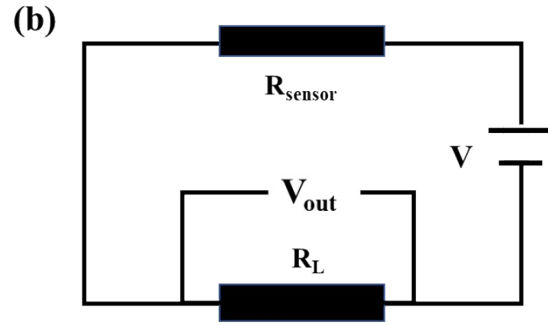
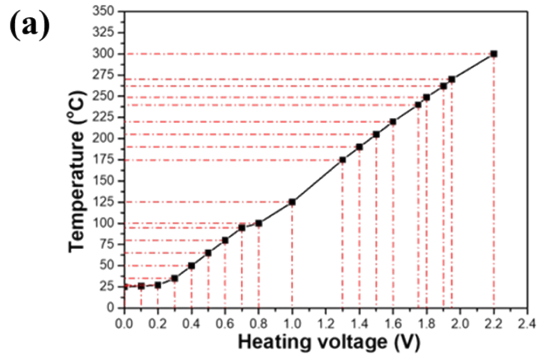
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164 **Fig. S13.** Optimized models of the adsorption of the H₂ molecules and energies on Pd₁-
 165 ZnS and Pd NPs-ZnS.

166



169 **Fig. S14.** Schematic of the fabrication for gas sensing system. (a) the gas sensing system
170 LP-002A, (b) the exploded views of test base, (c) MEMS sensors.



172

173 **Fig. S15.** (a) The relationship between the temperature and the voltage of MEMS gas
 174 sensors, (b) measuring circuit of MEMS sensors.

175

176 **TableS1.** EXAFS fitting parameters at the Pd *K*-edge for various samples*.

Sample	Shell	CN^a	$R(\text{\AA})^b$	$\sigma^2(\text{\AA}^2)^c$	$\Delta E_0(\text{eV})^d$	<i>R</i> factor
Pd foil	Pd-Pd	12	2.74			0.002
PdO	Pd-O	4.0	2.02			0.009
	Pd-Pd1	4.0	3.02			
	Pd-Pd2	8.0	3.41			
Pd ₁ -ZnS	Pd-S	4.3	2.34	0.0027	-6.3	0.004

177 ^a*CN*, coordination number; ^b*R*, the distance to the neighboring atom; ^c σ^2 , the Mean Square Relative

178 Displacement (MSRD); ^d ΔE_0 , inner potential correction; *R* factor indicates the goodness of the fit.

179 *This value was fixed during EXAFS fitting, based on the known structure of Pd. Fitting range: 2.6

180 $\leq k (\text{\AA}^{-1}) \leq 12.7$ and $1.4 \leq R (\text{\AA}) \leq 3.0$ (Pd foil), $2.5 \leq k (\text{\AA}^{-1}) \leq 12.4$ and $1.0 \leq R (\text{\AA}) \leq 3.6$ (PdO), 2.6

181 $\leq k (\text{\AA}^{-1}) \leq 10.6$ and $1.2 \leq R (\text{\AA}) \leq 2.2$ (Pd₁-ZnS).

182

183 **Table S2.** The content of noble metals in the obtained composites was measured by ICP-OES.
184

Samples	Zn ($\mu\text{g/ml}$)	Pd ($\mu\text{g/ml}$)	Content of Pd (wt%)
Pd ₁ -ZnS	8.308	0.0379	0.45
Pd NPs-ZnS	7.024	0.0368	0.52

185

186 **Table S3.** The summary of the response time(τ_{res}) of the sensors for the H₂ (1 ppm) sensing reaction.

Operating Temperature/ $^{\circ}\text{C}\cdot\text{K}^{-1}$	Response time/s		
	ZnS	Pd1-ZnS	Pd NPs-ZnS
140/413	12.25	7.52	11.25
150/423	11.78	6.35	10.25
160/433	10.48	6.27	9.55
170/443	10.48	5.42	8.95
180/453	9.45	5.02	8.34
200/473	6.43	/	6.52
220/493	5.13	/	5.22

187 When the obtained sensor response kinetics is governed by the adsorption process,
 188 the relaxation time (τ_{res}) can be written as a function of temperature according to the
 189 well-known thermal activation function.

190
$$\tau_{res} = \tau_0 \exp\left(\frac{E_{act}}{RT}\right)$$

191
$$\ln \tau_{res} = \ln \tau_0 + E_{act}/RT$$

192
$$\text{Slope} = E_{act}/R$$

193 Here, where τ_0 is the pre-exponential constant, which is determined only by the
 194 nature of the reaction and independent of the reaction temperature and gas
 195 concentration in the system; T is the working temperature (K) and R is the universal
 196 gas constant ($8.314 \text{ J}\cdot\text{mol}^{-1}\cdot\text{K}^{-1}$); E_{act} is the activation energies.

197

198 **Table S4.** The of QCM tests.

199

200

Sample	Fundamental frequency (10⁶ hz)	Frequency after coating (10⁶ hz)	Frequency shift (hz)	Load mass (ng)
ZnS	10003080.9	9998001.4	5079.5	2821.9
Pd NPs-ZnS	10002847.2	10002518.7	328.5	182.5
Pd₁-ZnS	10002986.1	10002704.2	281.9	156.61

201 **Table S5.** The summary of the reaction rate constants of ZnS, Pd₁-ZnS and Pd NPs-ZnS.

Sample	K_{ads} (ppm⁻¹S⁻¹)	K_{des} (S⁻¹)	K (K_{ads} / K_{des} ppm⁻¹)
ZnS	1.298*10 ⁻⁶	0.516	2.516*10 ⁻⁶
Pd NPs-ZnS	9.164*10 ⁻⁷	0.956	9.586*10 ⁻⁷
Pd₁-ZnS	2.465*10 ⁻⁶	1.964	1.255*10 ⁻⁶

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203

204 **Table S6.** The reported H₂ sensors and their gas sensing performances.

205

Sensing material	H ₂ Conc. (ppm)	Operating temperature (°C)	Response (R _a /R _g)	LOD (ppm)	Response/recovery times	Ref.
Pd-SnO ₂ nanosheets	100	200	33	0.45	10 s/62 s	5
ZnO/ZnS core-shell	1000 ppm	300	20%	500	/	6
ZnO NFs	10	350	150	0.1	>2 min/>5 min	7
Pd/SnO ₂ nanowires	100	150	4.5	1	> 5 min/ > 6 min	8
Pd/ZnO-SnO ₂ NFs	200	270	171	0.25	1 s/20 s	9
0.2%Pt-SnO ₂ nanoparticles	1%	200	150.2	200	60s/120s	10
Pd nanopattern	1000	25	1.5%	2.5	12s/30s	11
Hollow Pd-Sn alloy nanotubes	200	25	1.63%	1	20/18	12
Pd single-atom-Co ₃ O ₄	1000	125	80	/	15s/70s	13
1.5%Pd/ZnO	100	360	11.3	5	2s/5s	14
Pd/SiC	100	380	14.48	5	10/18	15
Pd-Au NDs/In ₂ O ₃ NCBs	500	280	45	0.3	5/3	16
PdO/WO ₃	10	150	76	5	5/113	17
Pd₁-ZnS	400	170	70.66	20	5.1/1.8	This work

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207

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